



2814

PATENT
2342-107P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Mitsuhiro HIRANO Conf.: 3165
Appl. No.: 08/813,200 Group: 2814
Filed: March 7, 1997 Examiner: M. DIETRICH
For: SUBSTRATE PROCESSING APPARATUS WITH LOCAB.
EXHAUST FOR REMOVING CONTAMINANTS (AS
AMENDED)

LARGE ENTITY TRANSMITTAL FORM

Assistant Commissioner for Patents
Washington, DC 20231

May 29, 2001

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Sir:

Transmitted herewith is an amendment in the above-identified application.

- The enclosed document is being transmitted via the Certificate of Mailing provisions of 37 C.F.R. § 1.8.
- The enclosed document is being transmitted via facsimile.

The fee has been calculated as shown below:

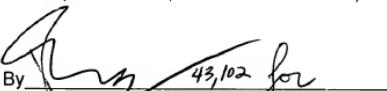
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR		PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	4	-	26	=	0	\$ 18	\$0.00
INDEPENDENT	4	-	4	=	0	\$ 78	\$0.00
<u> FIRST PRESENTATION OF A MULTIPLE CLAIM</u>						\$260	\$0.00
						TOTAL	\$0.00

- Petition for _____ month(s) extension of time pursuant to 37 C.F.R. §§ 1.17 and 1.136(a) is being filed, along with the necessary extension fees, together with the Notice of Appeal, concurrently herewith.
- No fee is required.
- A check in the amount of \$0.00 is enclosed.
- Please charge Deposit Account No. 02-2448 in the amount of \$0.00. This form is submitted in triplicate.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. §§1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP


By 43,102 for
Michael K. Mutter, #29,680

MKM/RLS/dsp
2342-107P

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(Rev. 04/19/2000)



PATENT
2342-0107P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Mitsuhiro HIRANO Conf.: 3165
Appl. No.: 08/813,200 Group: 2814
Filed: March 7, 1997 Examiner: S. RAO
For: SUBSTRATE PROCESSING APPARATUS WITH LOCAL EXHAUST FOR REMOVING CONTAMINANTS (AS AMENDED)

AMENDMENT

Assistant Commissioner of Patents
and Trademarks
Washington, D.C. 20231

May 22, 2001

Sir:

In reply to the Examiner's Office Action dated February 22, 2001, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

- Sub G1*
- F1*
-
10. (Four Times Amended) A substrate processing apparatus comprising:
a substrate processing chamber for processing a substrate;
a load lock chamber;
a gas supply for supplying gas into said load lock chamber;
a chamber exhaust for exhausting said load lock chamber, said chamber
exhaust including an atmospheric pressure vent line and a vacuum exhaust line, said

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